

# Spectroscopic properties of p-type Si sensors for X-ray spectroscopy

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# 1. Motivation – p-type Si and next-generation devices

- STFC is developing a **new generation of MHz frame-rate cameras** for the detection of hard X-rays (>20 keV).
- At these energies, high-Z semiconductors must be used to ensure sufficient photon stopping power; these materials are typically electron readout and has lead to the development of electron-sensitive readout chips.
- Certain applications, however, focus on low-energy photons (2-20 keV); the lower electron-hole-pair-generation energy of Si (3.62 eV cf. 4.67 eV for CZT) offers the potential of improved lower-energy spectral resolution.
- Unlike most Si sensors, those of p-type-Si are electron readout, allowing use of a single ASIC technology across multiple detectors and applications across multiple energy ranges.

# 2. Spectroscopic properties at low energy

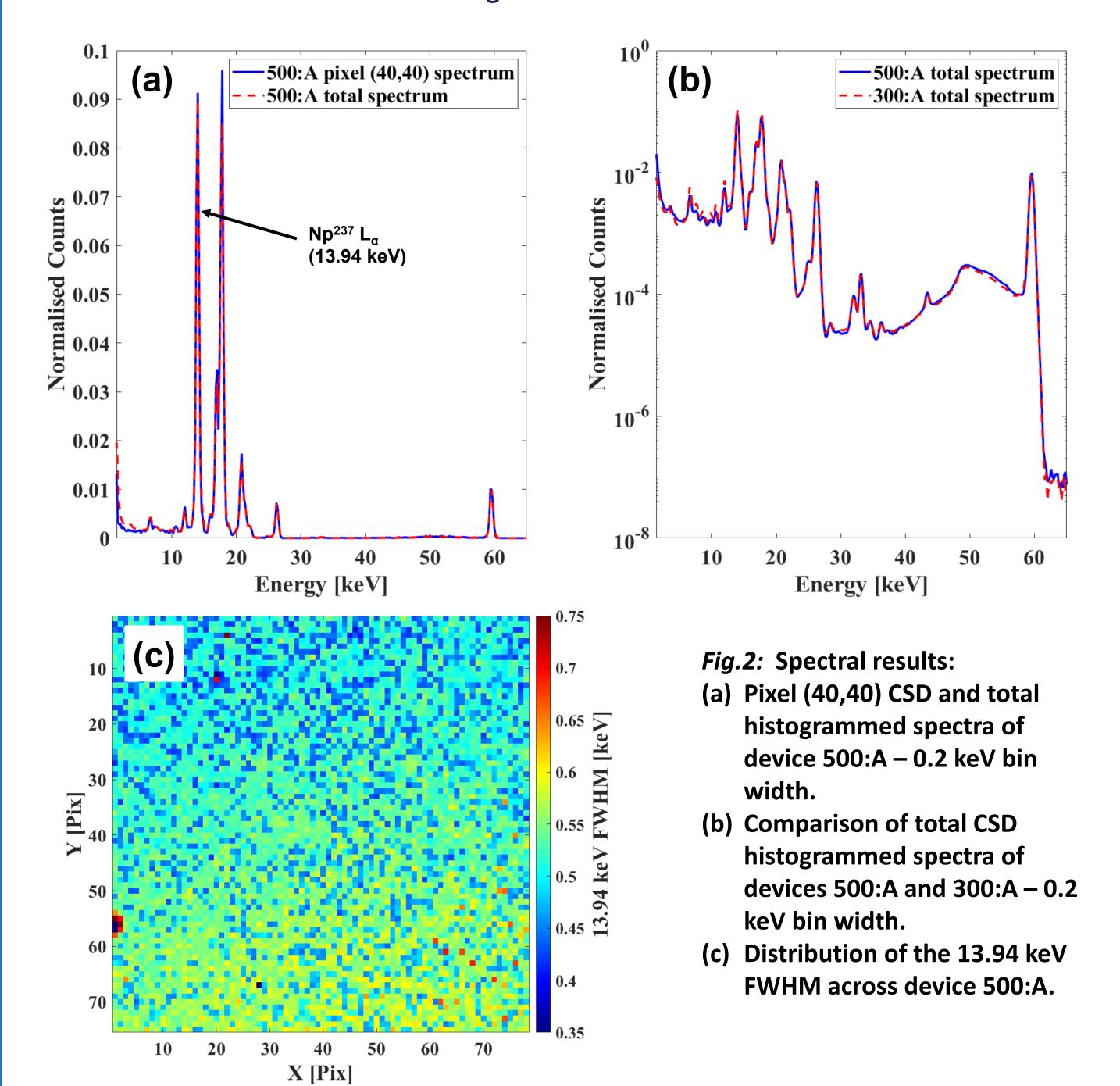
P-type Si, purchased from Micron Semiconductors Ltd. [1], was bonded to the STFC HEXITEC ASIC [2] and tested using a HEXITEC GigE system. Device specifications and HEXITEC operating conditions are given in Tab.1 below:

Tab.1: HEXITEC p-type Si properties.			
Quantity	Specification		
Pixel Pitch (μm)	250		
No. Pixels	80 x 76		
Frame Rate (kHz)	1.5		
Sensor thickness (µm)	300/500		
Applied bias (-V)*	180/300		

Fig.1: 500 μm P-type Si sensor bonded to the HEXITEC ASIC.

\*Investigated and selected to achieve both a high collection efficiency and low leakage current

Each device was irradiated for 1 hour with an 183 MBq <sup>241</sup>Am sealed source (placed 6 cm from device). Charge-sharing discrimination (CSD) and Gaussian fits to the resulting 13.94 keV <sup>237</sup>Np L<sub>α</sub> photopeak in each pixel provided estimates of the FWHM and thus the spectral resolution at 13.94 keV. Results for 500 µm device 500:A and 300 µm device 300:A are shown in Fig.2. below:



Tab.2: 13.94 keV FWHM of tested p-type Si devices.

Device	500:A	500:B	300:A	300:B
Thickness [μm]	500	500	300	300
FWHM at 13.94 keV [keV] (σ)	0.52 (0.05)	0.54 (0.06)	0.50 (0.08)	0.49 (0.08)

[3] Veale et al Sensors, 20, 28-32, 2747, 2020

# 3. Charge-sharing characteristics

- Results show ~79.97% of events are in a single 250 µm pixel pitch for 500 μm devices operated at -300 V; cf. 84.56% of events for 300 μm devices.
- However, the energy of these remaining events can be recovered chargesharing addition (CSA) analysis, shown in Fig.3, reveals minimal charge loss within the bulk and inter-pixel gap.

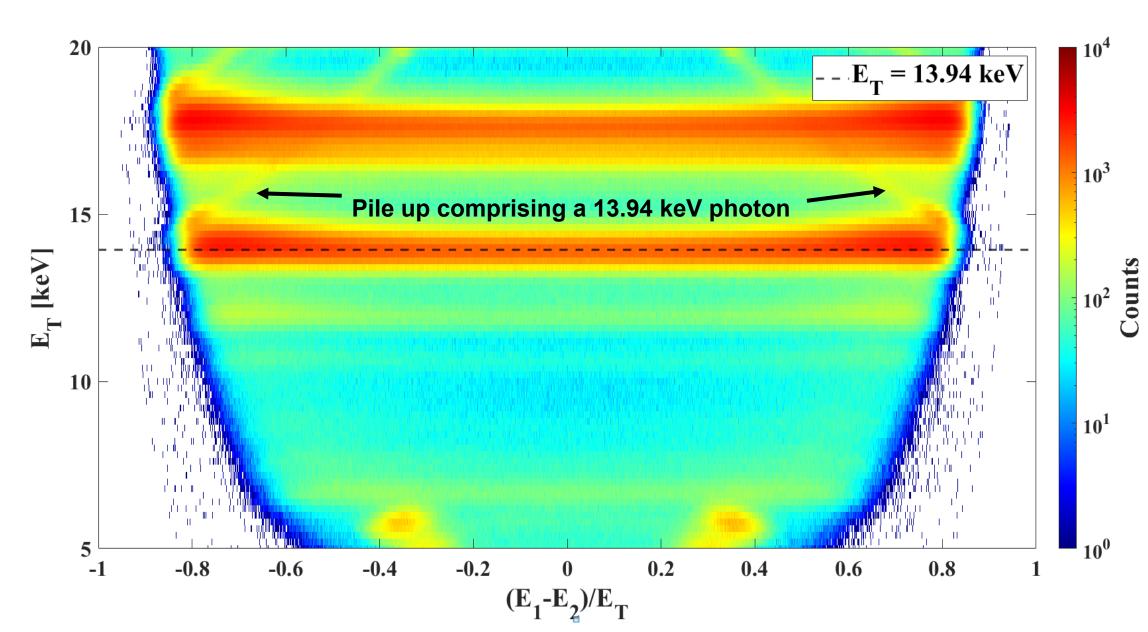


Fig.3: Plot of the total energy ( $E_{T}$ ) and the normalised difference between recorded energies  $(E_1, E_2)$  for two-pixel events in device 500:A; charge loss in 13.94 keV events is given by negative deviations from the dotted line.

### 4. Temporal stability

- Detector applications at photon-science facilities or in industry may require operation for extended periods; the temporal stability was assessed for device 500:A through continuous operation and exposure to an <sup>241</sup>Am sealed source for ~30 hours (20 min datasets collected every 80 min).
- Fig.4 demonstrates the spectral stability, with counts in the 13.94 keV peak ( $\pm 1\sigma$ ) fluctuating by <0.36% during this period.

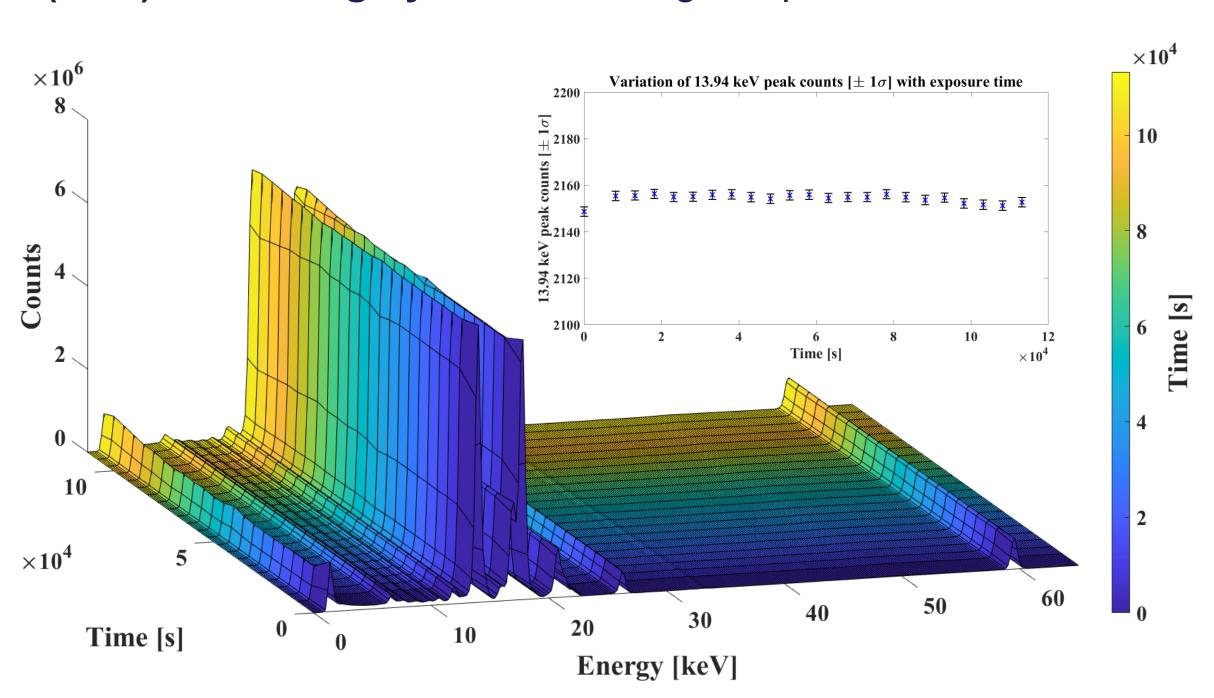


Fig.4: Evolution of the CSD global spectrum of sensor 500:A over ~30 hours; inset is a plot of the fluctuation of 13.94 keV peak counts ( $\pm 1\sigma$ ) with exposure time.

#### 5. Conclusion

All devices tested (Tab.2) display high resolution and highly-uniform spectroscopic performance at 298 K. The 0.49 ± 0.08 keV average value measured for device 300:B is the highest resolution measured to date using HEXITEC (cf. 0.83 keV at 59.54 keV utilising CZT [3]).